

Tungsten doped vanadium oxide thin films by
atmospheric pressure chemical vapour deposition.

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Vanadium oxide thin films can be applied to a variety of technological appliances including solid state batteries, electrochromic devices and infrared modulators. In particular vanadium(IV) oxide has been suggested as a potential intelligent window coating (1) due to its metal-to-semiconductor transition (MST) at 68 °C (2). The transition involves a monoclinic to tetragonal structural change, which is accompanied by dramatic changes in electrical and optical properties. The low temperature phase is infrared transparent while the high temperature phase is infrared reflective.

Doping metal ions into the vanadium(IV) oxide lattice has been shown to affect the transition temperature of the metal-to-semiconductor transition in bulk materials (3) and thin films (4). The direction and magnitude of the switch from VO₂ monoclinic to VO₂ tetragonal depends on the nature of the dopant with tungsten being the most effective at lowering the transition temperature (4).

Tungsten doped vanadium oxide thin films on glass substrates were prepared from atmospheric pressure chemical vapour deposition reaction of vanadium(IV) chloride, tungsten(VI) ethoxide and water. At substrate temperatures > 600 °C and at 10:1 water to VCl₄ ratio, tungsten doped VO₂ could be produced. The films were examined by micro Raman spectroscopy, glancing angle X-ray diffraction, reflectance-transmittance spectroscopy, X-ray photoelectron spectroscopy, Rutherford backscattering spectroscopy, scanning electron microscopy and energy dispersive analysis of X-rays.

The tungsten-doped VO₂ films displayed lower transition temperatures compared to the pure compound, a desirable effect for the proposed application. The films showed a thermochromic switching that was related to tungsten content as shown in Figure 1.

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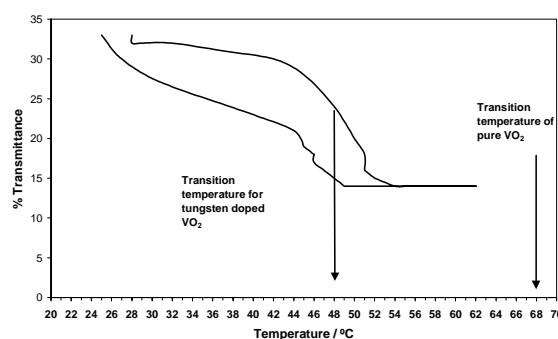


Figure 1. % transmittance at 2.5 μm vs temperature for ~1% tungsten doped VO₂ thin film showing reduced thermochromic transition temperature compared to pure VO₂.